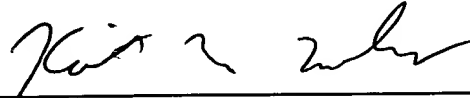


If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/6303/KMT.

Respectfully submitted,



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Attorney for Applicant(s)

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PTO/SB/08a (08-03)

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Sheet 1

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9

Application Number

09/965,370

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September 26, 2001

First Named Inventor

Chung, et al.

Group Art Unit

1762

Examiner Name

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Attorney Docket Number

AMAT/6303/CPI/COPPER/PJS

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	A2	US-6660660 B2	12/09/2003	Haukka, et al.	
	A3	US-6632279 B1	10/14/2003	Ritala, et al.	
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Sheet 2

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Group Art Unit

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09/965,370

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Group Art Unit

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Sheet 7

of 9

Application Number

09/965,370

Filing Date

September 26, 2001

First Named Inventor

Chung, et al.

Group Art Unit

1762

Examiner Name

Eric B. Fuller

Attorney Docket Number

AMAT/6303/CPI/COPPER/PJS

Submission Date

August 27, 2004

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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**SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT BY
APPLICANT**

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Sheet 1 of 9

Application Number	09/965,370
Filing Date	September 26, 2001
First Named Inventor	Chung, et al.
Group Art Unit	1762
Examiner Name	Eric B. Fuller
Attorney Docket Number	AMAT/6303/CPI/COPPER/PJS
Submission Date	August 27, 2004

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		Country Code ² -Number ⁴ -Kind Code ⁵ (if known)				
	B18	WO 02/31875 A2	04/18/2002	Haukka, et al.		
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Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
	C1	Applied. Phys. Lett. 71 (25), December 22, 1997 (3604-6)	
	C2	Chang-Wook, <i>et al.</i> "Growth and Characterization of Aluminum Oxide (Al ₂ O ₃) Thin Films by Plasma-Assisted Atomic Layer Controlled Deposition," J. Korean Inst. Met. Mater., Vol. 38, No. 10, Oct. 2000 pp.1395-1399	
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Sheet 9

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9

Application Number

09/965,370

Filing Date

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First Named Inventor

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Group Art Unit

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Examiner Name

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	C12	Martensson, <i>et al.</i> "Cu ₂ as Copper Source in Atomic Layer Epitaxy," Chemical Vapor Deposition. Proceedings of the Fourteenth International Conference and EUROCVI-11 (1997), pp. 1529-36	
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	C25	PCT Written Opinion for PCT/US02/28715 DATED July 28, 2004 (AMAT/6303-PCT)	

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